



Docket No. 016004963 CT

#15113  
5/23/2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi IKEDA, et al.

GAU: 1754

SERIAL NO: 09/463,961

EXAMINER: T. VANOY

FILED: May 25, 2000

FOR: METHOD AND APPARATUS FOR PROCESSING EXHAUST GAS OF SEMICONDUCTOR  
FABRICATION

REQUEST FOR EXTENSION OF TIME  
UNDER 37 C.F.R. 1.136

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

It is hereby requested that a **three** month extension of time be granted to May 21, 2002 for

☐ filing a response to the Official Action dated:

☐ responding to the requirements in the Notice of Allowability dated:

☐ filing the Formal Drawings. The Issue Fee due

has been timely filed.

☐ responding to the Notice to File Missing Parts of Application dated:

☒ filing a Notice of Appeal. A timely response to the Final Rejection and a two month extension of time fee was filed on April 19, 2002.

☐ filing an Appeal Brief. A Notice of Appeal was filed on:

☐ Applicant claims small entity status. See 37 CFR 1.27. Therefore, the fee amount shown below is reduced by one-half.

The required fee of \$840.00 is enclosed herewith by check and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.

Norman F. Oblon

Registration No. 24,618

Corwin P. Umbach

Registration No. 40,211



22850

Tel. (703) 413-3000  
Fax. (703) 413-2220  
(OSMMN 10/01)

05/22/2002 AWONDAF1 00000146 09463961

02 FC:117

520.00 OP

RECEIVED

MAY 23 2002

TC 1700